

Challenges and Improvement Actions for HPC Wafer Testing



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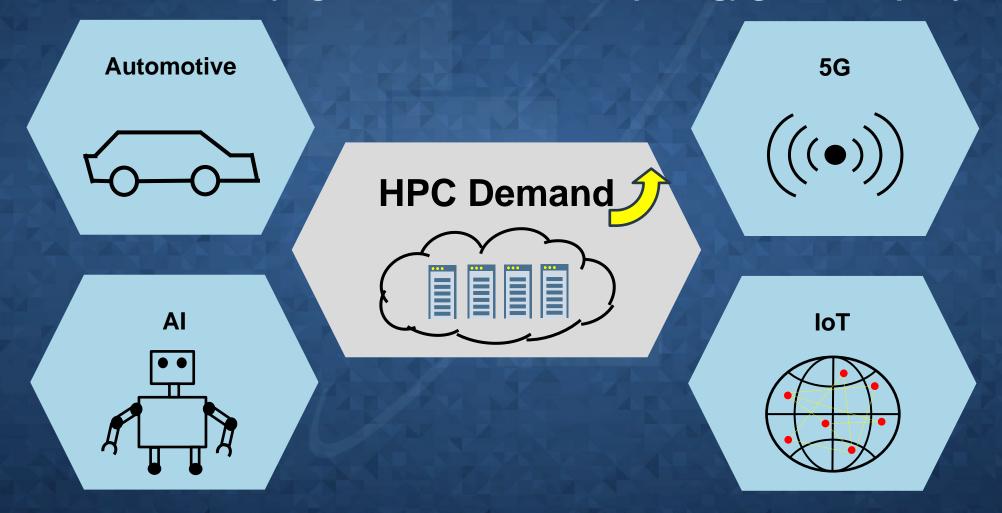
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Overview

- Introduction
- HPC Challenges
 - High Force
 - High Power
 - High Temperature
- Summary

HPC Demand

The demand of HPC (High Performance Computing) growth rapidly.



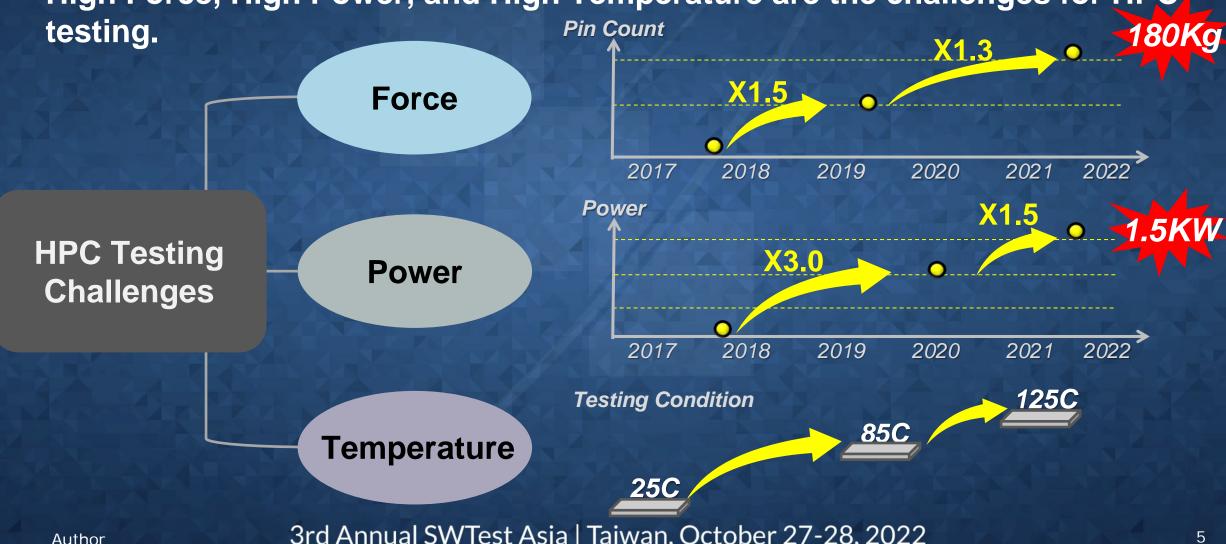
HPC Testing Challenges

 With the development of technology node and advanced integration process, the device complexity increase.



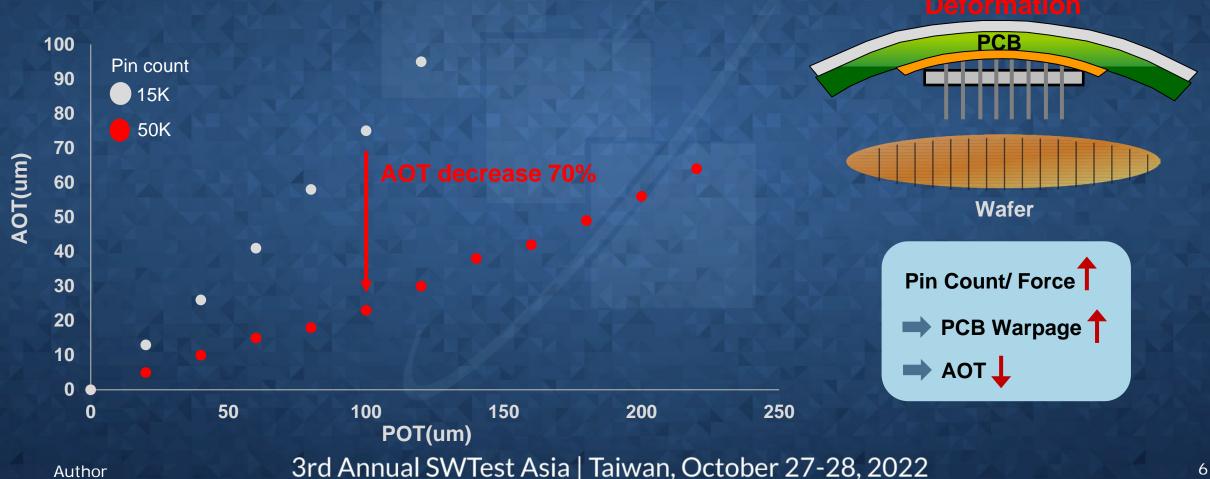
HPC Testing Challenges

High Force, High Power, and High Temperature are the challenges for HPC



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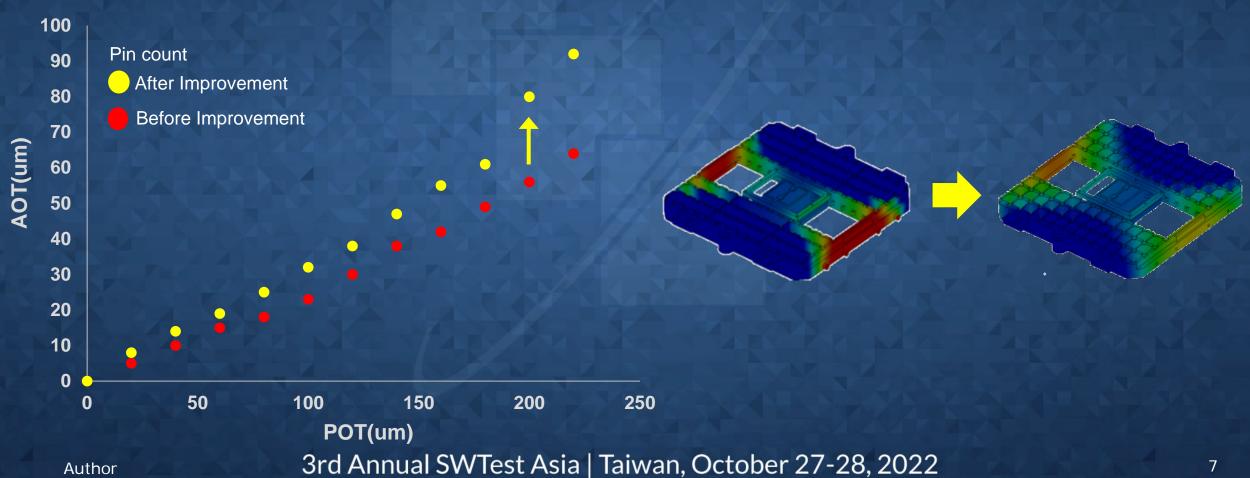
- Observation
 - For high pin count probe card, AOT decrease obviously caused by PCB deformation.



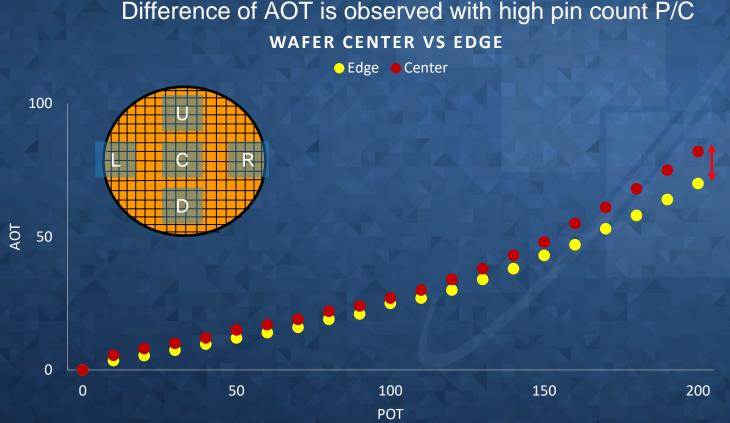
Improvement Action

Author

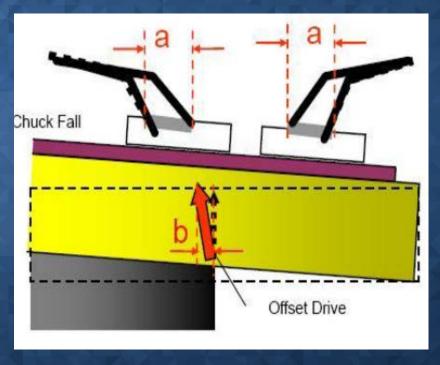
► Improve AOT 43% by (1) Stiffener Structure Enhancement (2) Material Enhancement.



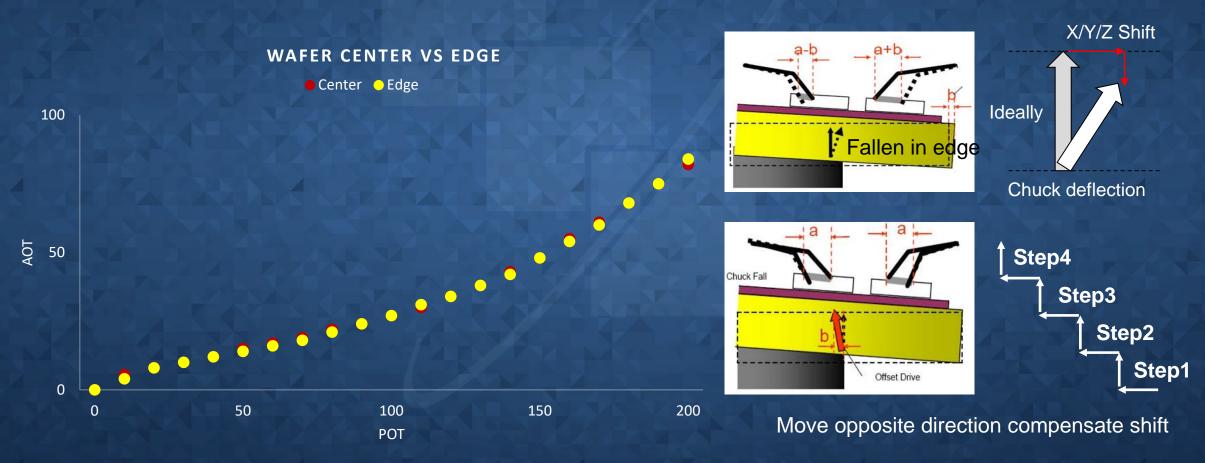
- Observation
 - The non-uniform AOT is observed with high pin count testing.



Chuck Deflection issue

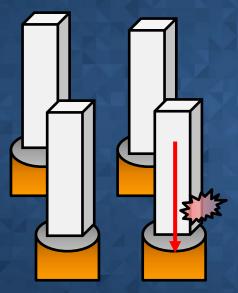


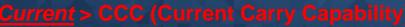
- Improvement Action
 - Enable chuck offset function to compensate chuck bending issue.



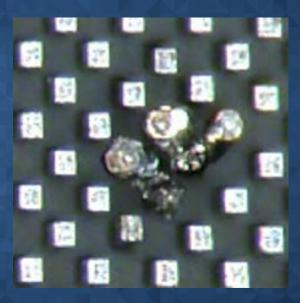
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- Observation
 - The higher tip burnt rate is observed in HPC testing.

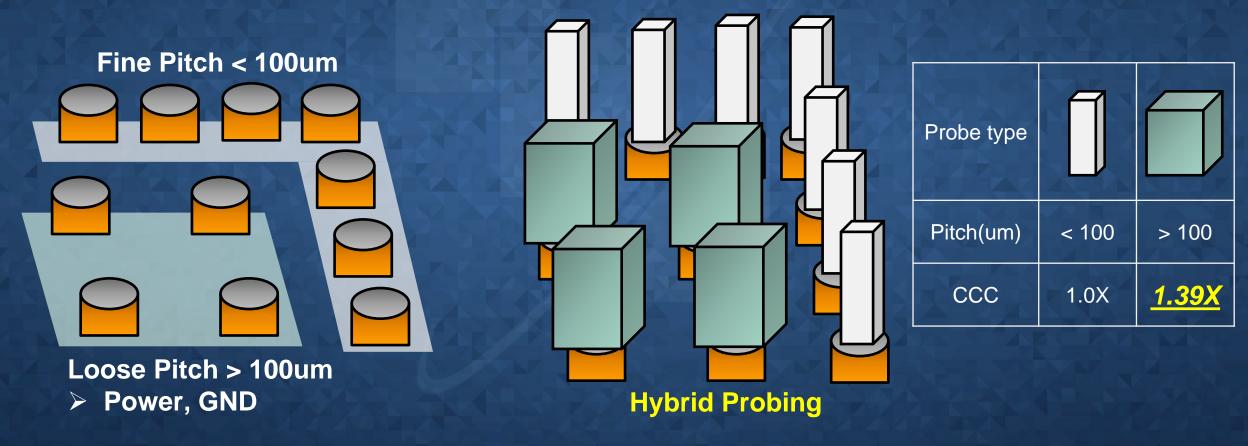








- Improvement Action
 - Hybrid probing: The probe with higher CCC is used in pitch > 100um.

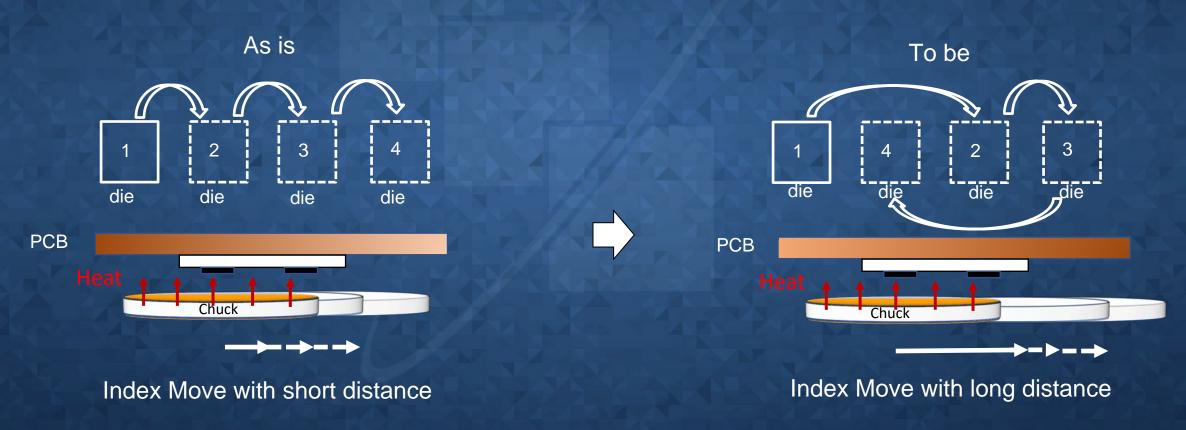


Observation :

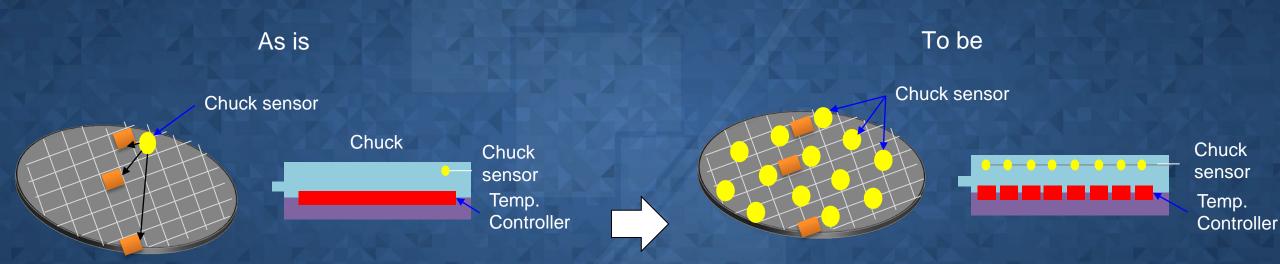
Temperature accuracy and heat dissipation will be challenges under high power testing.



- Improvement Action
 - 1) Index move optimization: Index move is changed from short distance to long distance to improve PCB temperature uniformity.



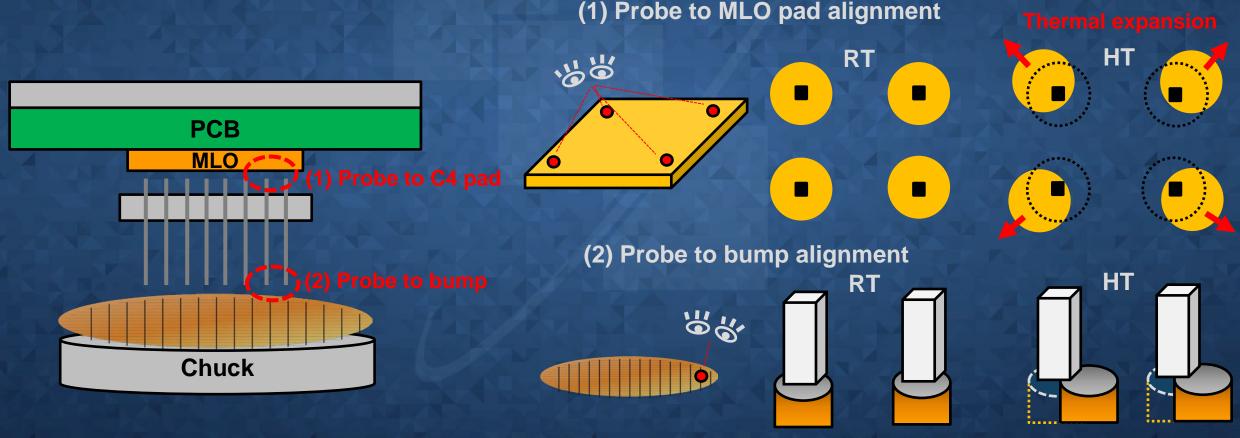
- Improvement Action
 - 2) Control temperature actively by multiple sensor and control zones.



One sensor chuck Temp. control from 1 point temp.

Multi sensor chuck
Temp. control with individual area

- Observation
 - Due to CTE(Coefficient of Thermal Expansion) difference, the alignment of (1) <u>Probe to MLO pad</u> (2) <u>Probe to bump</u> will shift at high temperature testing condition.



- Improvement Action
 - > To improve the alignment, we can optimize below factors.

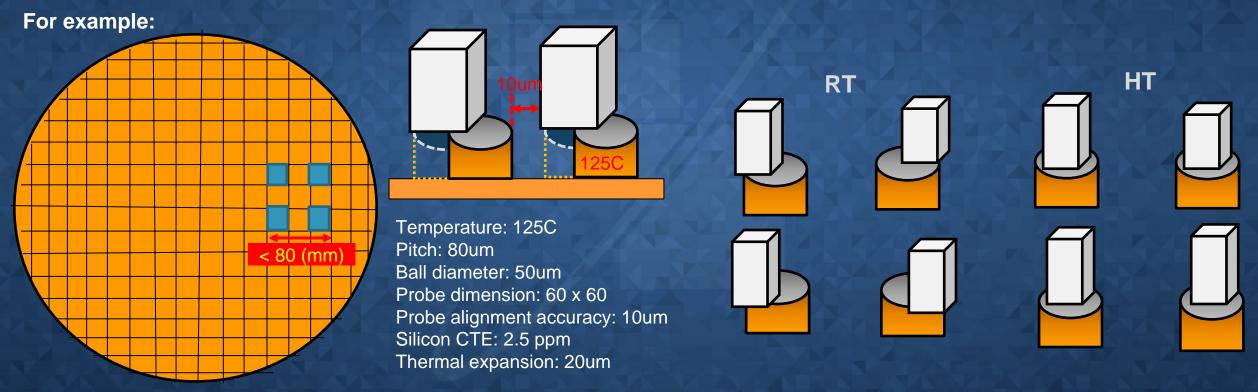
Parts	Key Factors	Controllable
MLO	Pad size	0
	Manufacture Tolerance	0
	CTE	X
Probe Head	Scaling	0
	CTE	X
Wafer	Probing Area	0
	Pitch	X
	CTE	X
	Testing temperature	X
	Bump size	X
Prober/ Chuck	CTE	X
	Alignment Technology	0

- Improvement Action for (1) <u>Probe to MLO pad</u> alignment
 - 1) Control the scaling of MLO dimension toward negative tolerance.
 - 2) Enlarge MLO Pad size to avoid contact issue.
 - 3) Design scaled UD to compensate MLO thermal expansion.



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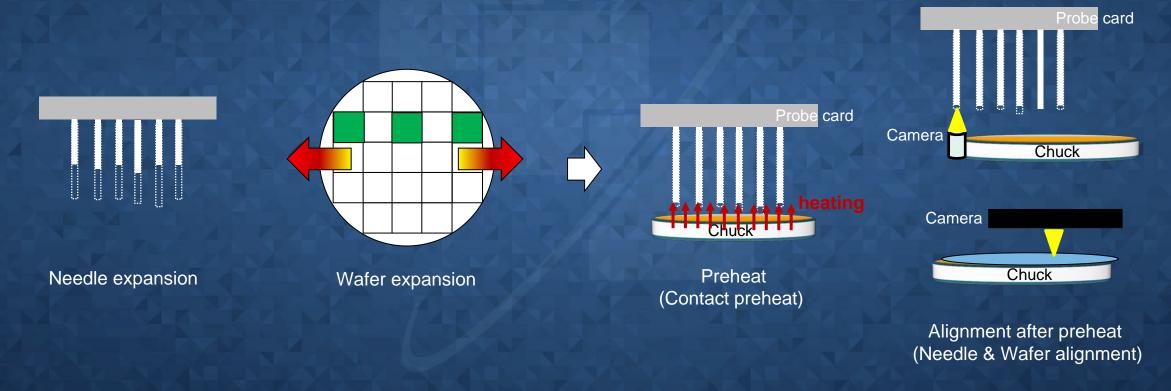
- Improvement Action for (2) <u>Probe to bump</u> alignment
 - 1) Constrain probing area.
 - 2) Design scaled LD to compensate wafer thermal expansion.



Constrain probing area

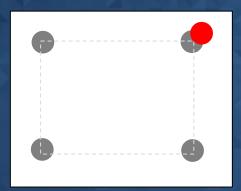
Design scaled LD to compensate

- Improvement Action for (2) <u>Probe to bump</u> alignment
 - 3) Execute preheat function and total alignment before testing to make sure needle height and wafer position are stable after thermal expansion.

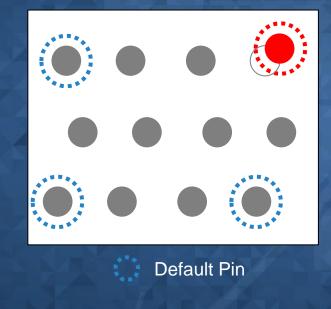


- Improvement Action for (2) <u>Probe to bump</u> alignment
 - 4) Enable more pin alignment function to make sure precise alignment.

AS IS (4 pin alignment)



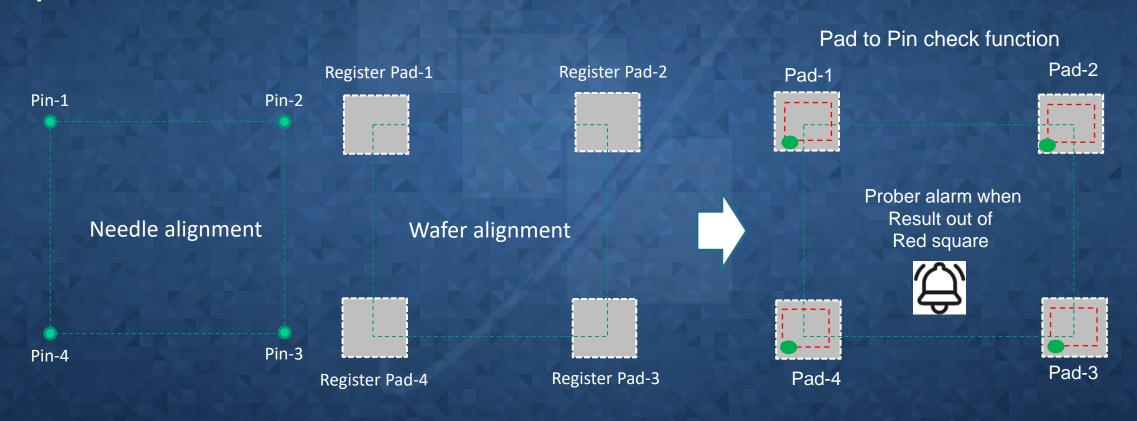
If 1 pin shift have Probe Mark Shift Risk



TO BE (> 4 pins alignment) Default Pin Additional Pin

Probe Center (θ) = Pin data angle (θ) + Card angle (θ) + Offset

- Improvement Action for (2) <u>Probe to bump</u> alignment
 - 5) Enable Pad to Pin check function to forecast contact position and pre-alert before production.



Summary

- The demand of HPC chip increase significantly.
- The challenges and improvement actions are studied.

HPC Characteristics	Challenges	Improvement Actions
Force	PCB Deformation	Enhance stiffener structure
	Chuck Bending	Enable 3D offset function
Power	Tip burnt	Hybrid probe
	Temperature control	Index move optimization
		Multiple sensor and control zones
Temperature	Probe to MLO Pad alignment	Control the scaling of MLO dimension
		Enlarge MLO Pad size
		Design scaled UD
	Probe to bump alignment	Constrain probing area
		Design scaled LD
		Enable more Pin alignment
		Enable Pad to Pin check